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United States Patent [19]

Matsumura

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[45] **Date of Patent: ** Jun. 13, 2000**

[54] **CONTACTOR FOR SEMICONDUCTOR IC TESTERS**

[75] Inventor: **Shigeru Matsumura**, Tokyo, Japan

[73] Assignee: **Advantest Corporation**, Tokyo, Japan

[**] Term: **14 Years**

[21] Appl. No.: **29/109,356**

[22] Filed: **Aug. 13, 1999**

Related U.S. Application Data

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[30] **Foreign Application Priority Data**

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Apr. 21, 1998	[JP]	Japan	10-11417
Apr. 21, 1998	[JP]	Japan	10-11418

[51] **LOC (7) Cl.** **13-03**

[52] **U.S. Cl.** **D13/182**; D13/147

[58] **Field of Search** D13/147, 182, D13/184; D10/75; 257/48, 690, 692, 693, 697

[56] **References Cited**

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[57] **CLAIM**

The ornamental design for a contactor for semiconductor IC testers, as shown and described.

DESCRIPTION

FIG. **1** is a perspective view of another embodiment of FIG. **1**;

FIG. **2** is a top plan view in a reduced scale of FIG. **1**;

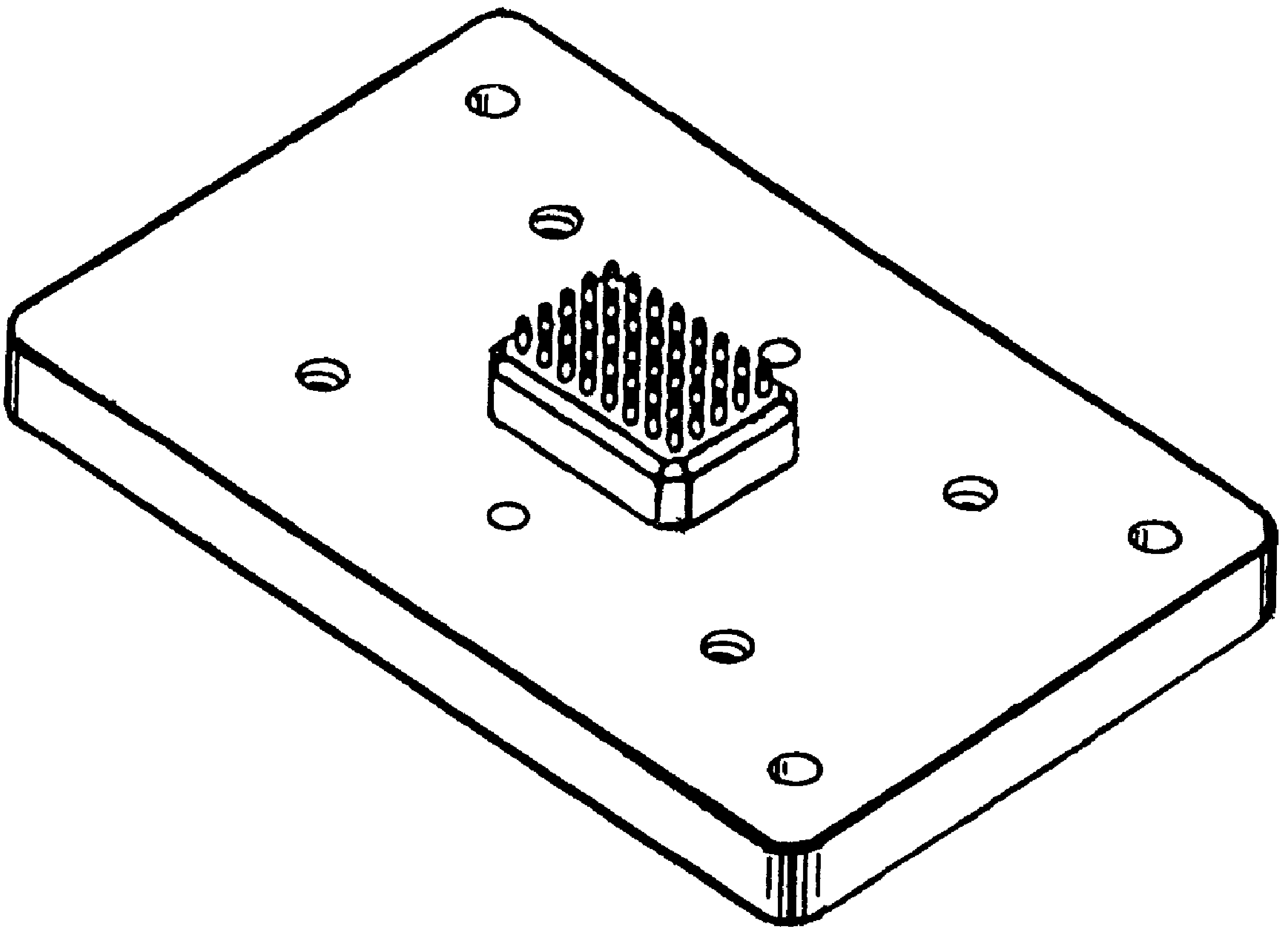
FIG. **3** is a bottom plan in a reduced scale of FIG. **1**;

FIG. **4** is a front elevational view in a reduced scale of FIG. **1**, the rear elevational view being a mirror image of the front elevational view;

FIG. **5** is a left side elevational view in a reduced scale of FIG. **1**, the right side elevational view being a mirror image of the left side view; and,

FIG. **6** is a center horizontal cross-sectional view in an enlarged scale of FIG. **2**.

1 Claim, 1 Drawing Sheet



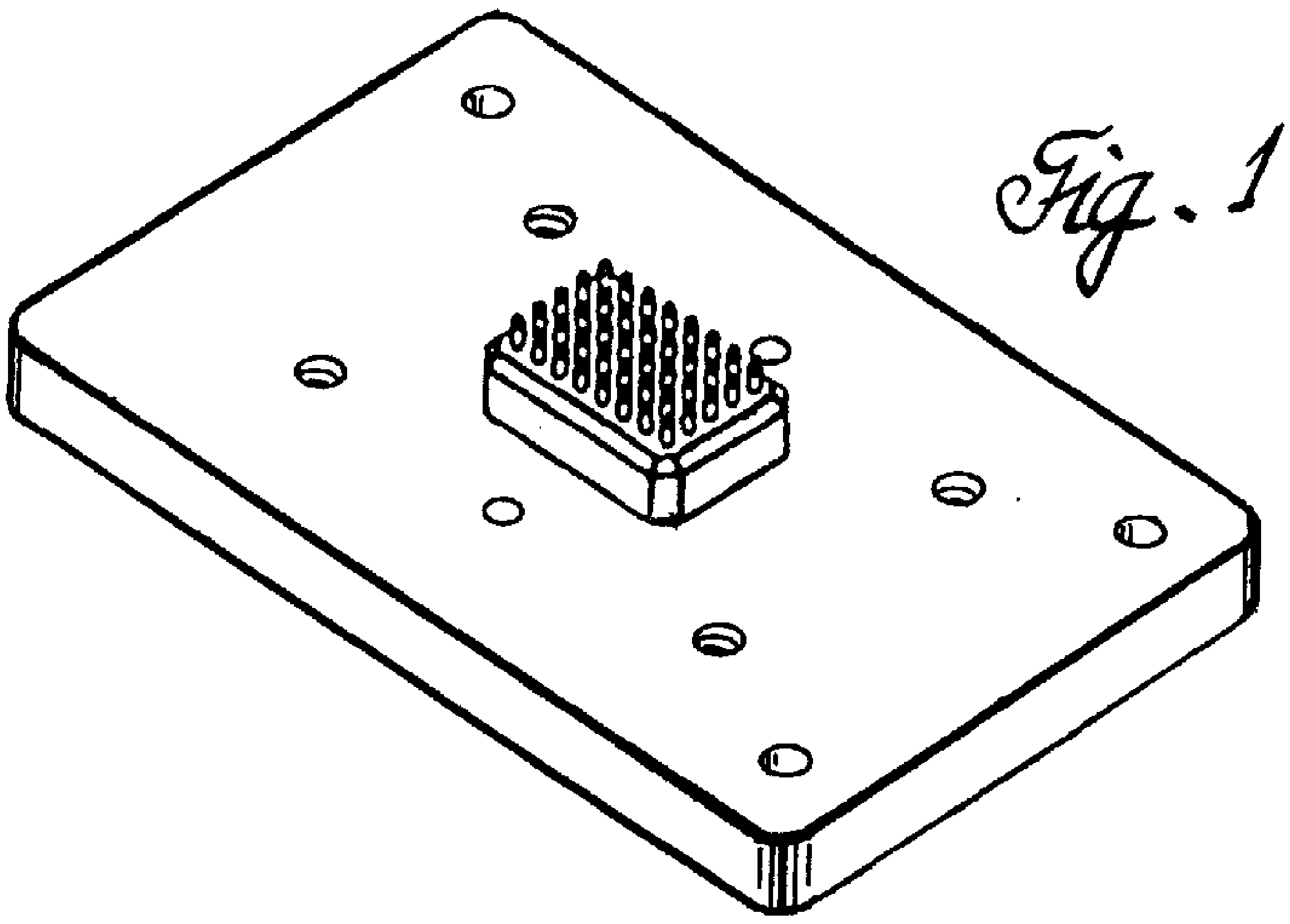


Fig. 1

Fig. 2

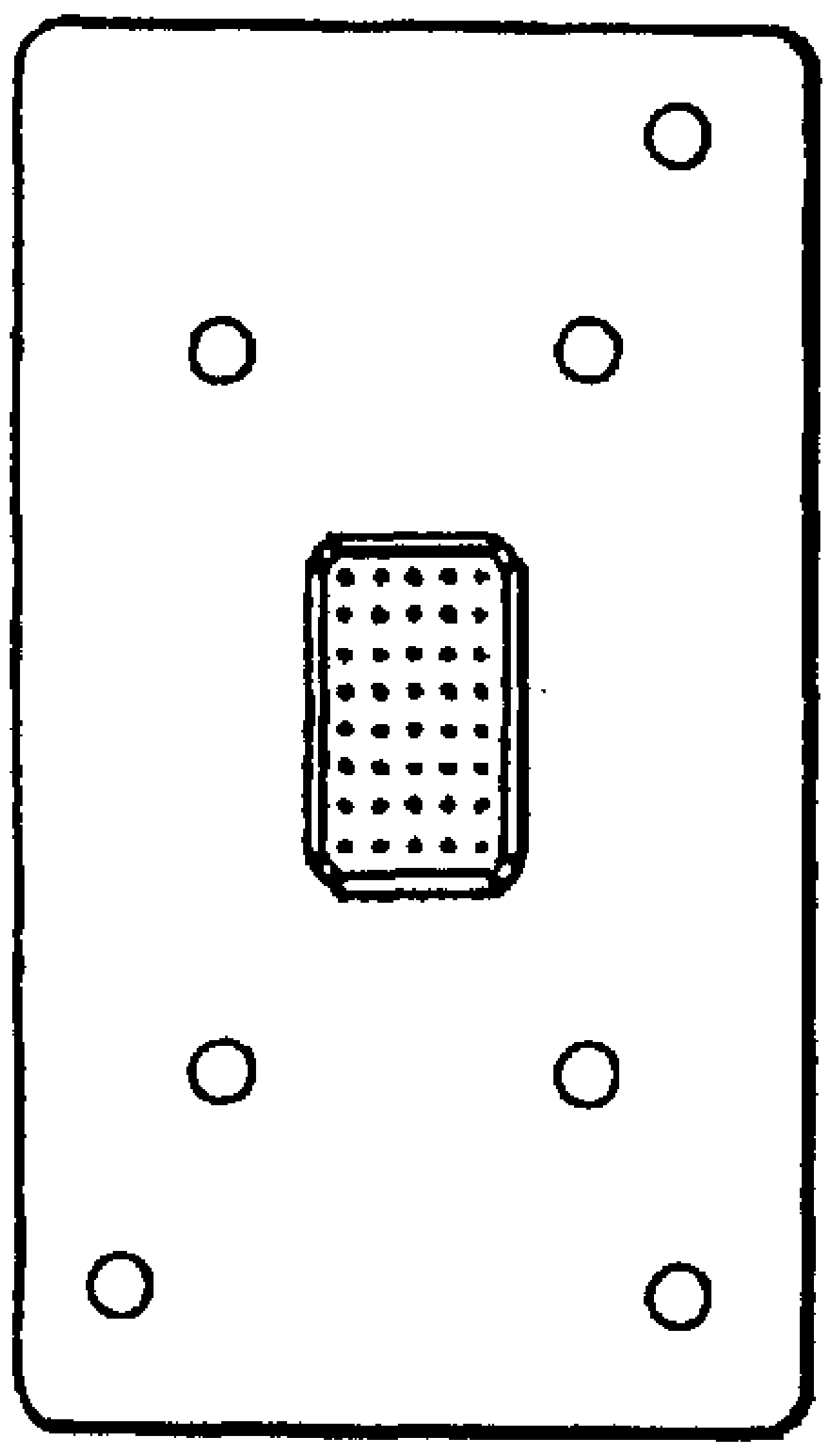


Fig. 3

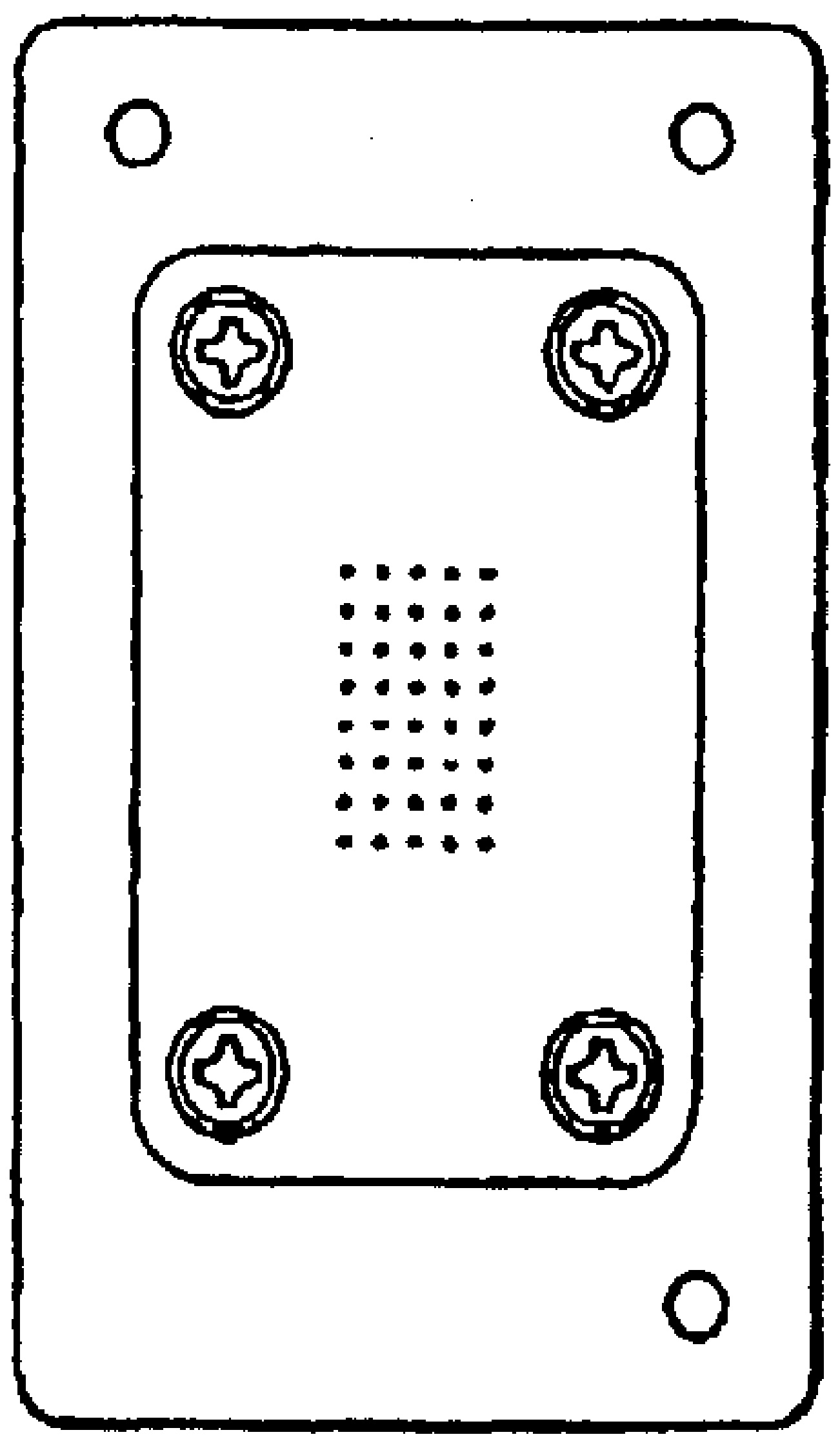


Fig. 4

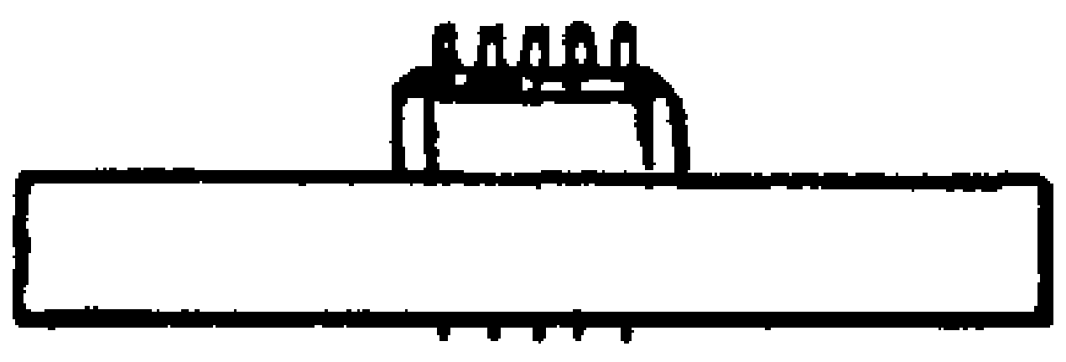


Fig. 5

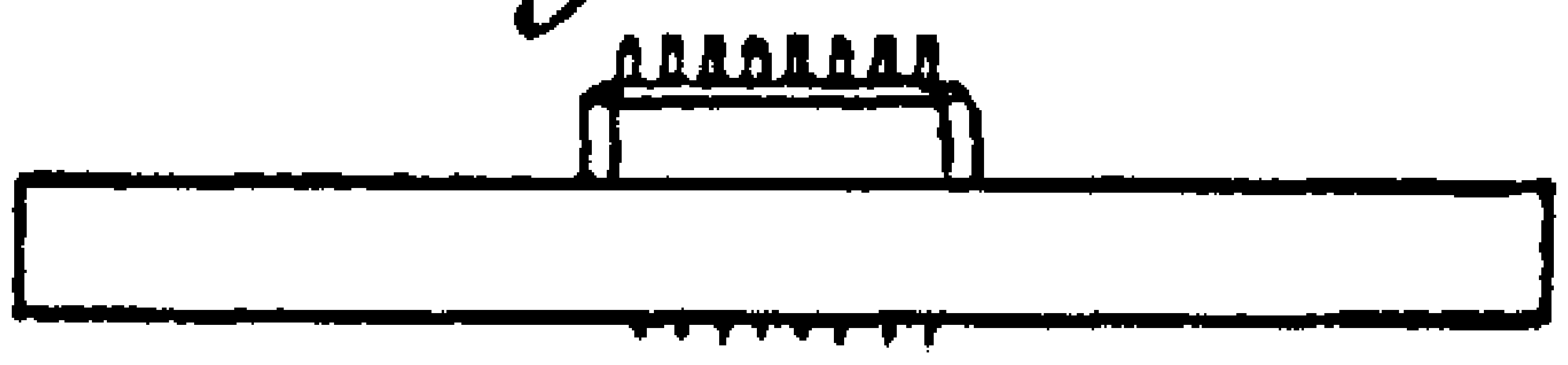


Fig. 6